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## \*BIBDATASHEET\*

Bib Data Sheet

**CONFIRMATION NO. 9071** 

SERIAL NUMBER 10/625,407	FILING DATE 07/23/2003 RULE	CLASS 219	GROUP ART 3742	UNIT	ATTORNEY DOCKET NO. TWI-8570		
APPLICANTS							
Michial Duff Howell, Felton, CA;							
Barry Roy Bowman, Dublin, CA;							
** CONTINUING DATA **********************************							
Foreign Priority daimed	yes 🗗 no	STATE OR	SHEETS	TOTAL	INDEPENDENT		
35 USC 119 (a-d) conditions met Verified and Acknowledged Ex	Allowance	cOUNTRY		CLAIMS 8	CLAIMS 1		
ADDRESS STALLMAN & POLLOCK LLP Suite 290 121 Spear Street San Francisco , CA 94105							
TITLE Method and apparatus for preparing semiconductor wafers for measurement							
			☐ All F	ees			
	·				1.16 Fees ( Filing )		
No	6: Authority has been given to charge/cre		1.17 Fees ( Processing Ext. of time )				
RECEIVED No 375	for following:		1.18 Fees ( Issue )				

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	*	☐ Credit
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